

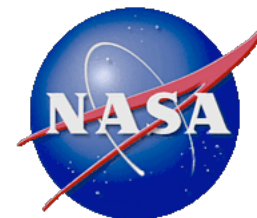
# Increased Rate of Multiple-Bit Upset at Large Angles of Incidence

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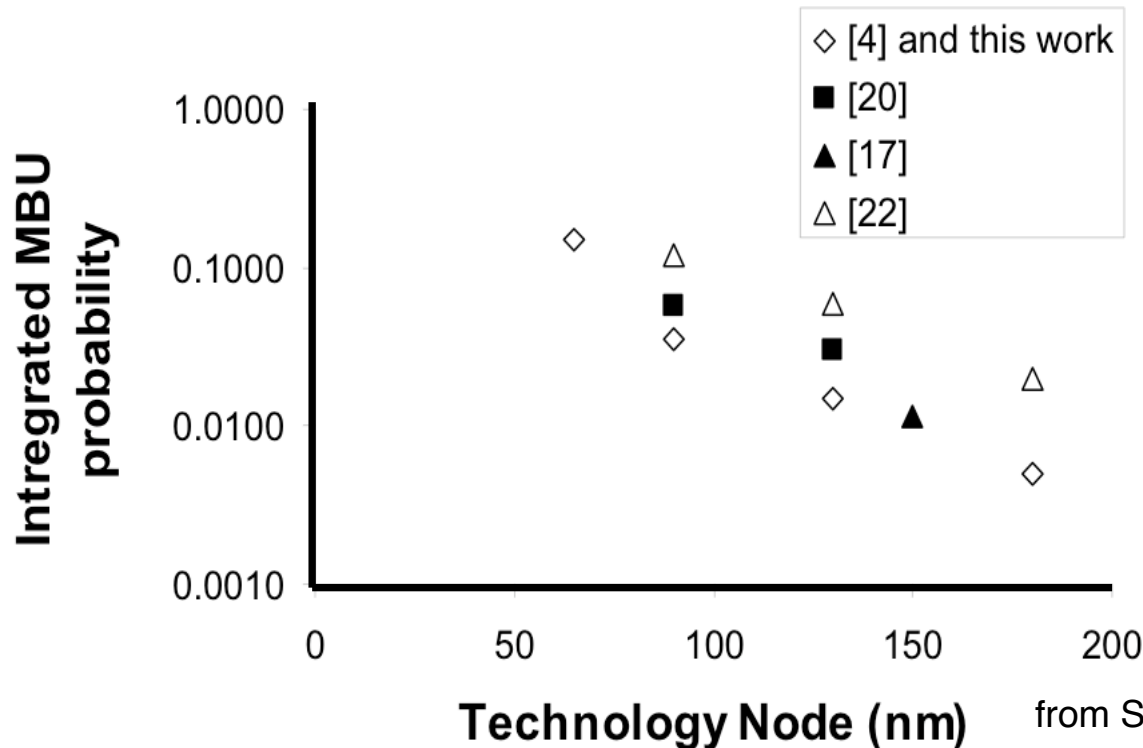


# Outline

- Background
  - Multiple-bit upset (MBU)
  - Neutron-induced MBU
- Experimental
  - Single-bit
  - Multiple-bit
- Modeling
  - Monte-Carlo Radiative Energy Deposition (MRED)
- Summary
  - Future work



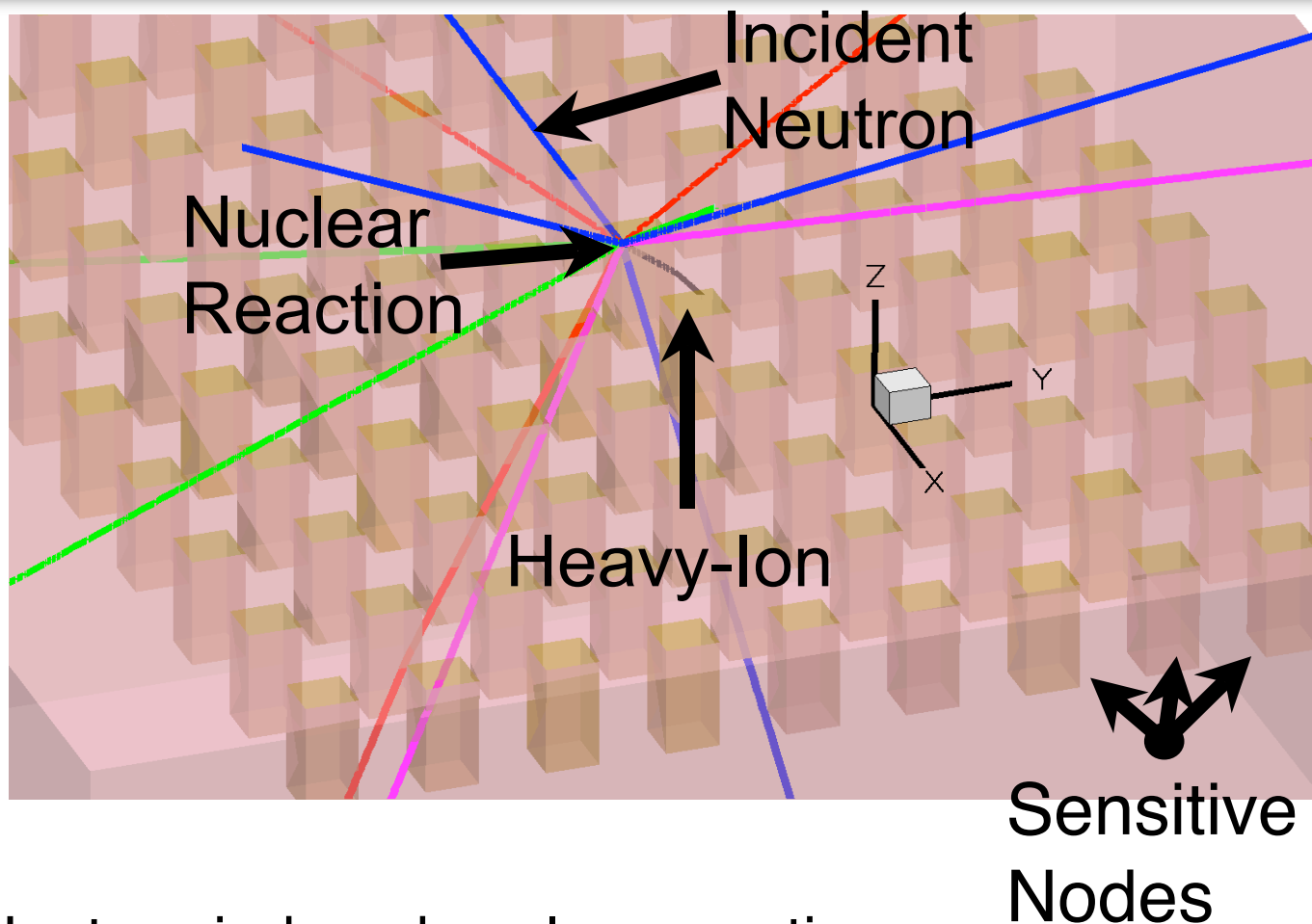
# Multiple-bit upset increases with scaling



- Multiple-bit upset (MBU) increases for smaller technologies
- Feature size small relative to radiation events
- MBU 2 or more physically adjacent bits



## Secondary products induce soft errors

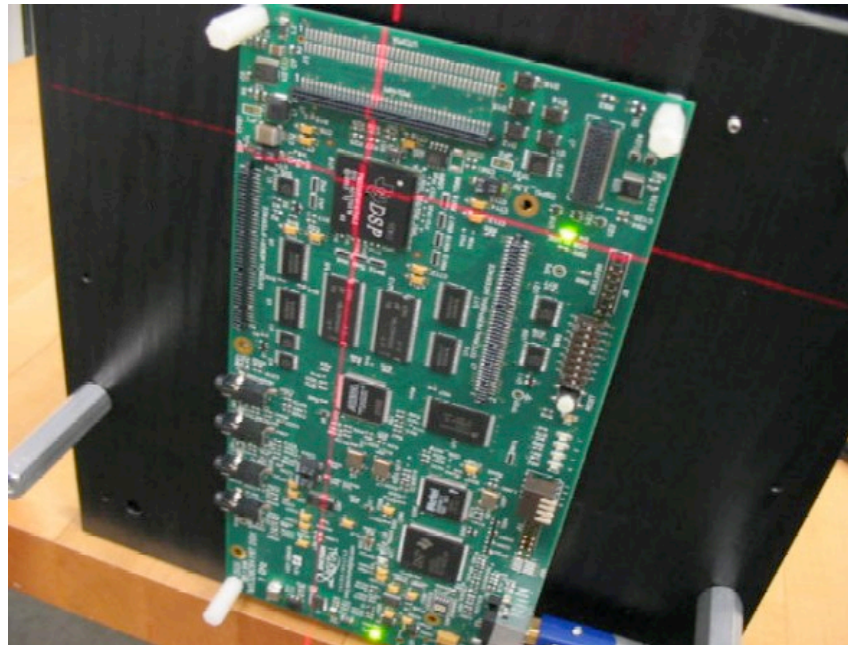


- Neutron-induced nuclear reactions

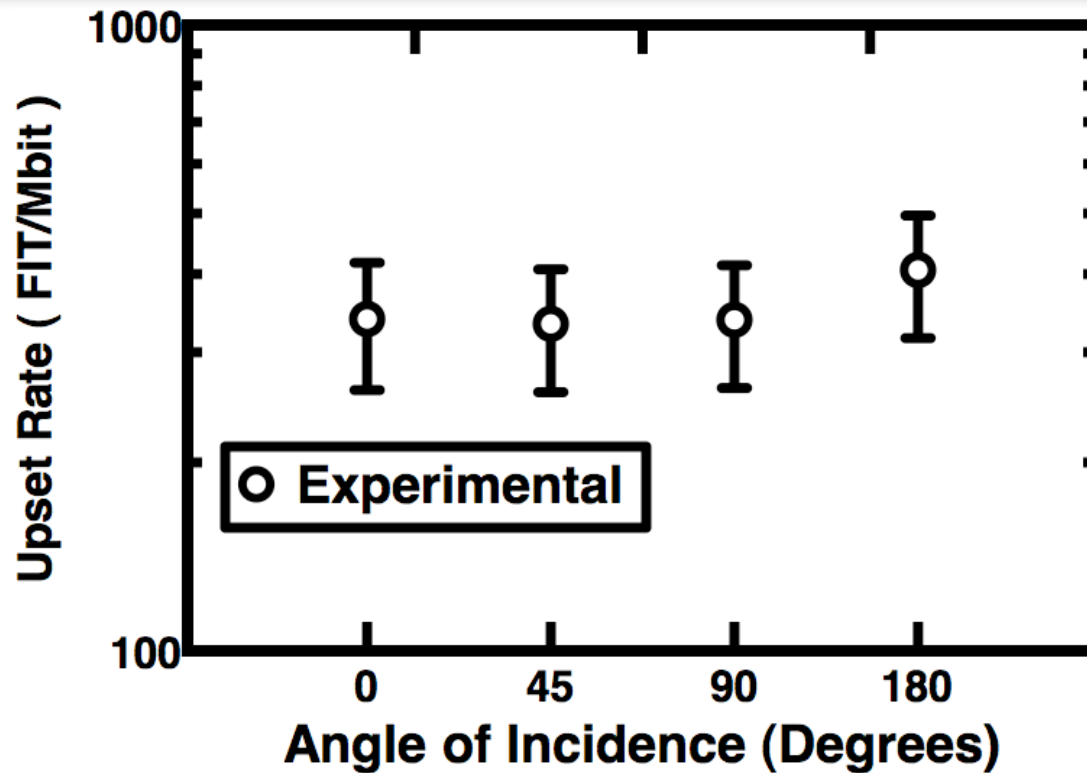


## Device under test is a TI 90 nm SRAM

- TI 90nm CMOS high performance (C027)
- DSP embedded SRAM (8MEG) @ 1.2 V
- LANL WNR Neutron beam line
- Test conditions - 0°, 45°, 90°, & 180°



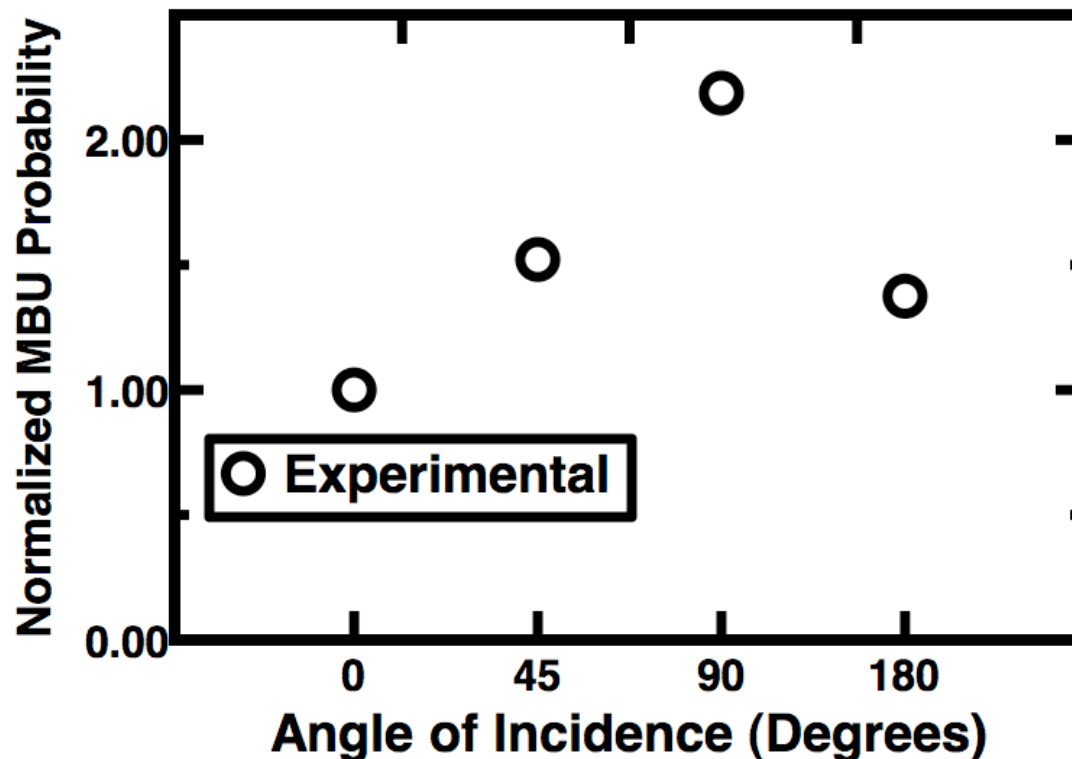
## Single-bit rate is not angle dependent



- No angular dependence



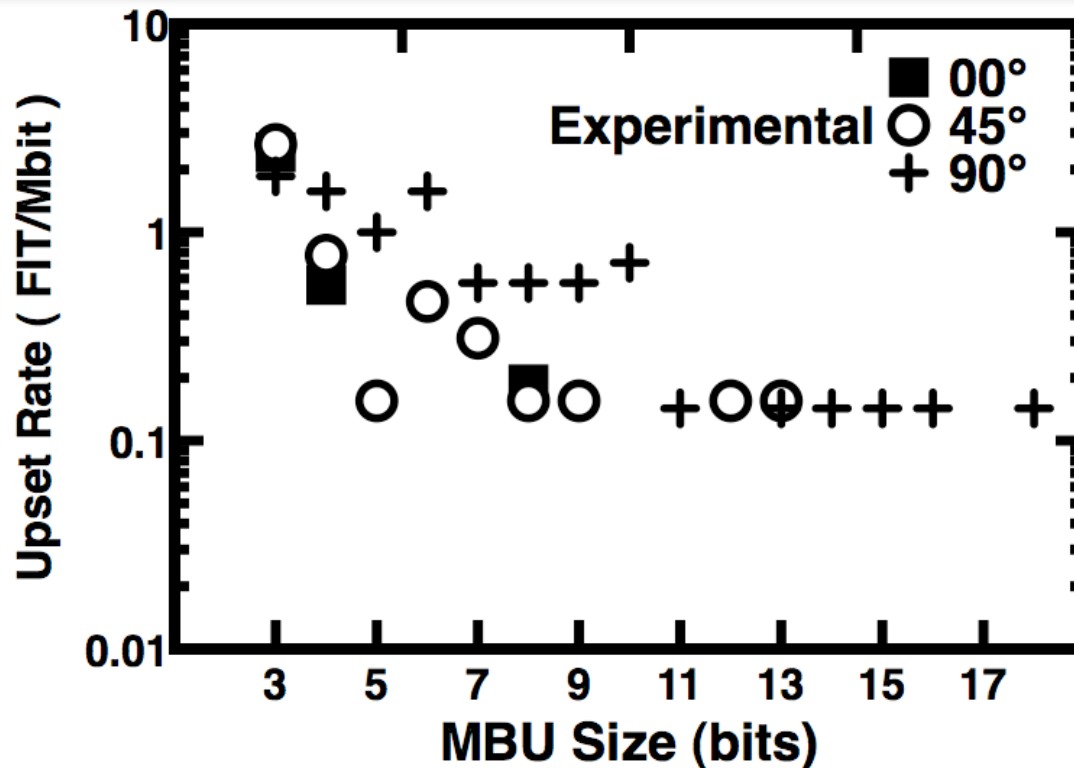
# Multiple-bit probability depends on device orientation



- MBU  $\equiv$  2 or more physically adjacent bits
- Probability of MBU  $\equiv$  (# of MBU events)/(# of total events)
- Normalized to 0°



# MBU multiplicity is higher at large angles



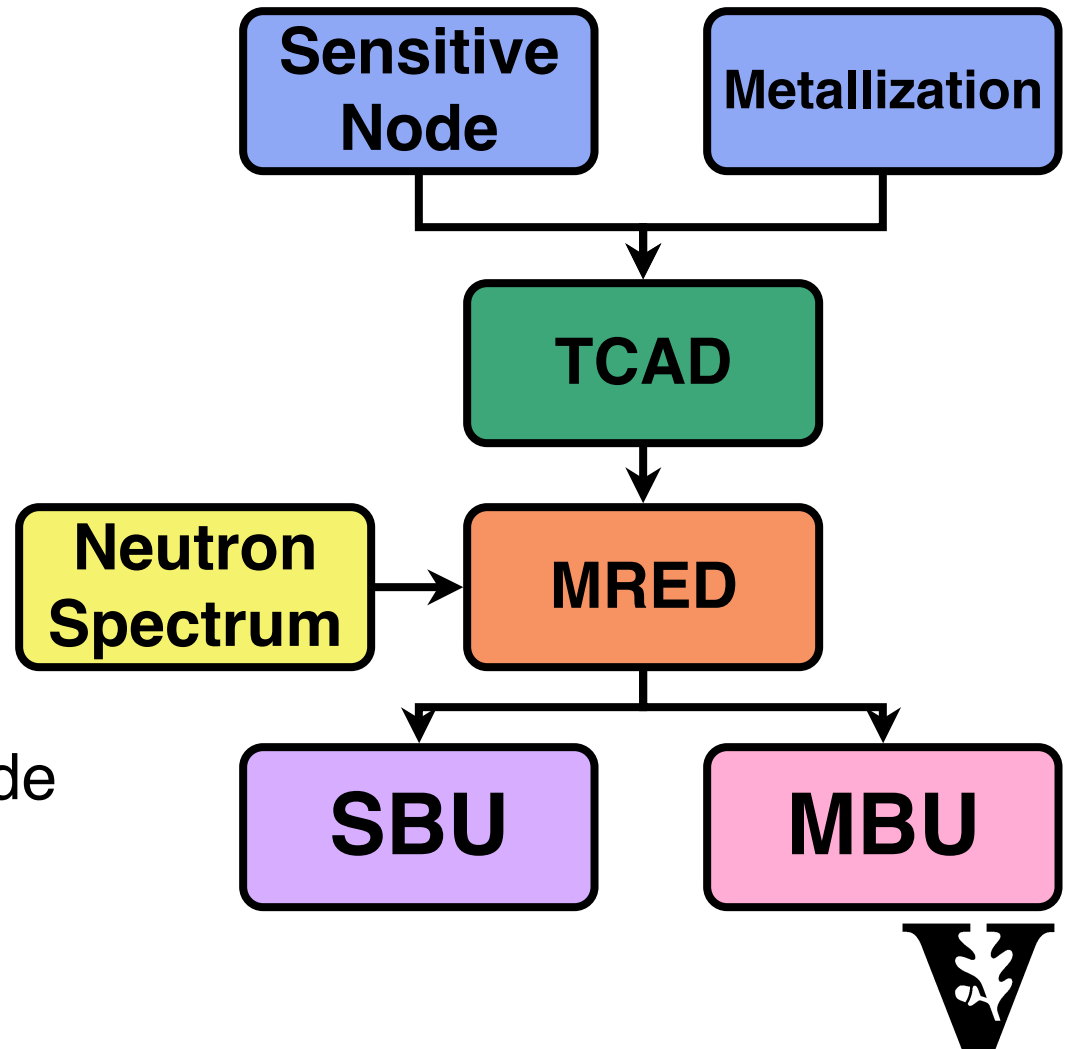
- Large angles show most number of MBU events
- Large angles show largest MBU events





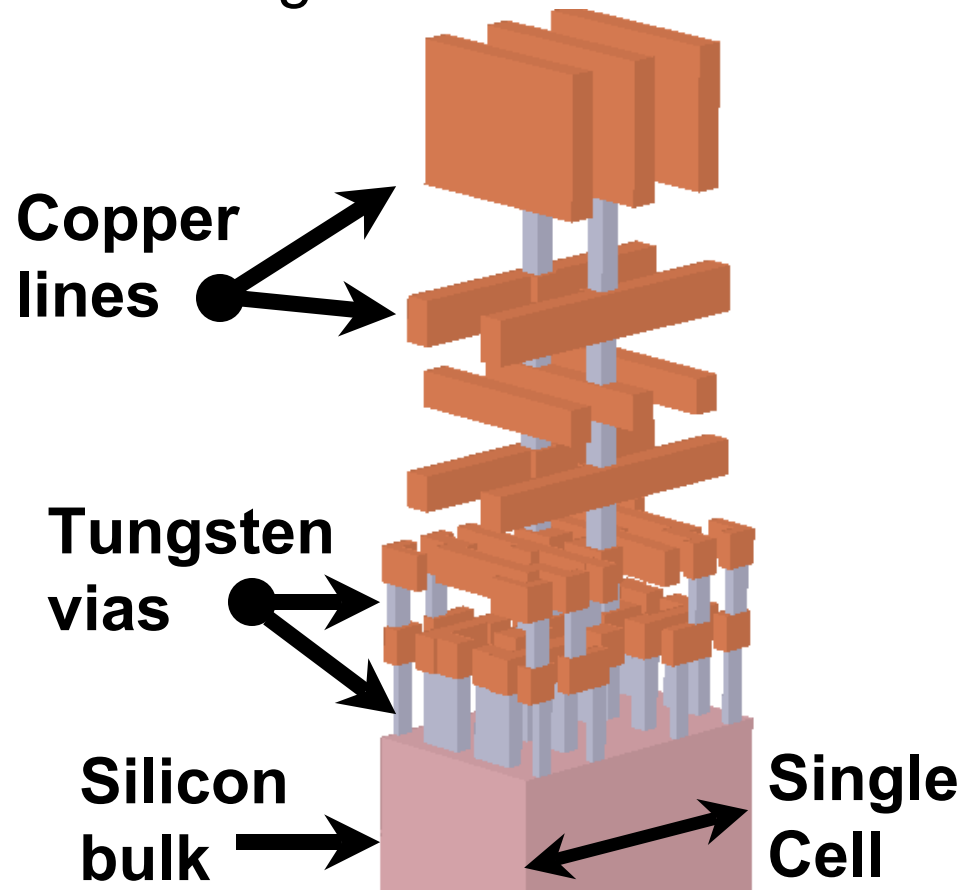
## Modeling methodology

- TI 90 nm SRAM model
- Sensitive node
  - Charge collection volume
- Technology Computer Aided Design (TCAD) Model
- Simulation - MRED (Monte-Carlo Radiative Energy Deposition) Code
- Single bit
- Multiple bit

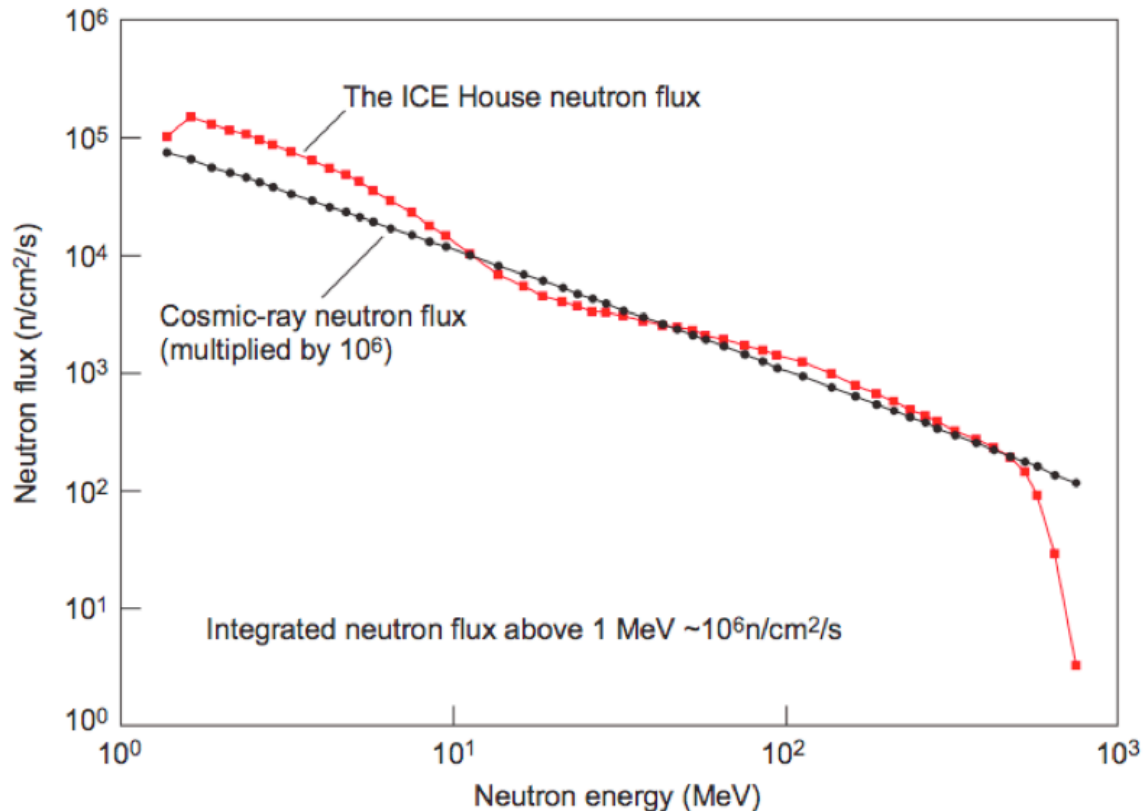


## MRED simulated the TCAD device

- TCAD structure created from TI layout and process
- Device simulated using LANL beam line neutron spectrum



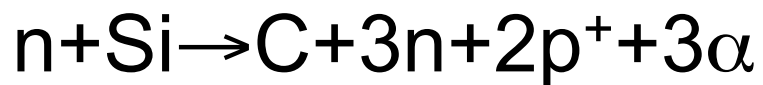
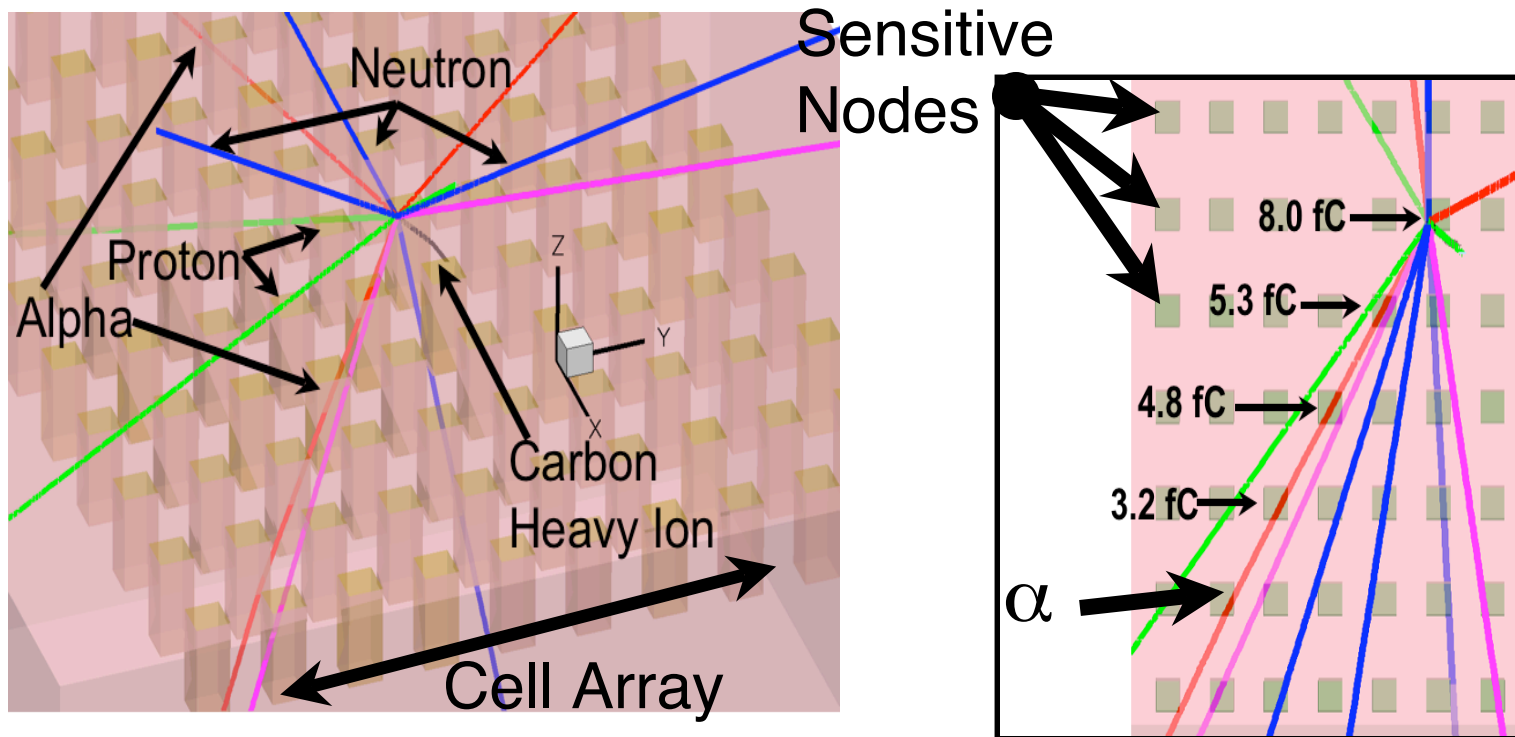
# LANL neutron beam



- WNR beam spectrum imported into MRED
- Fluence comparable to cosmic-ray neutron fluence



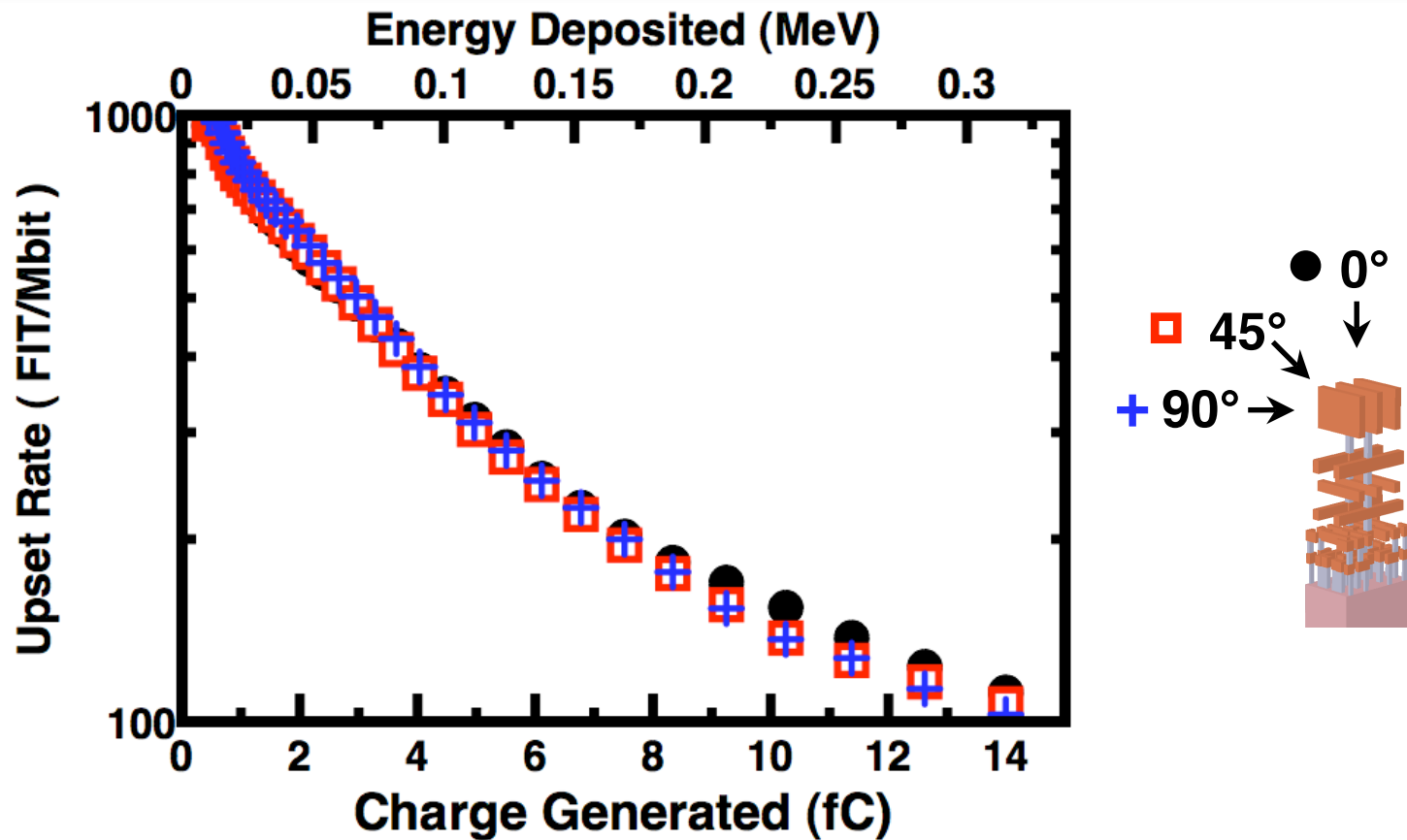
# MRED simulates ionization and nuclear processes



- MRED tracks energy deposition through all layers
- MRED calculates energy deposition at each node



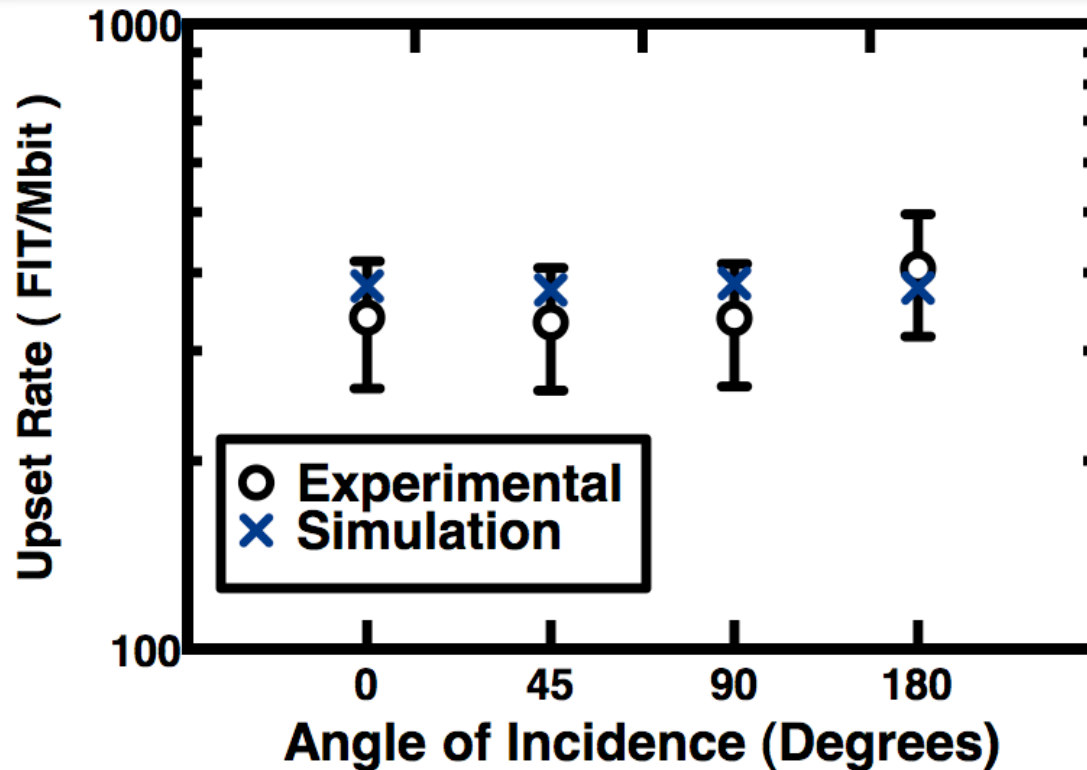
# Single-bit rate does not depend on orientation



- No angle dependence
- No frontside-backside dependence



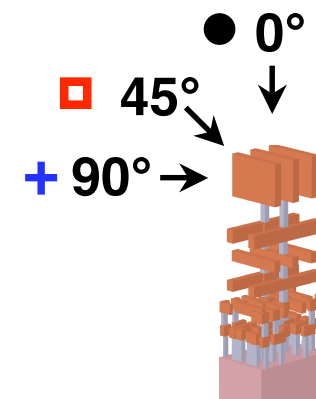
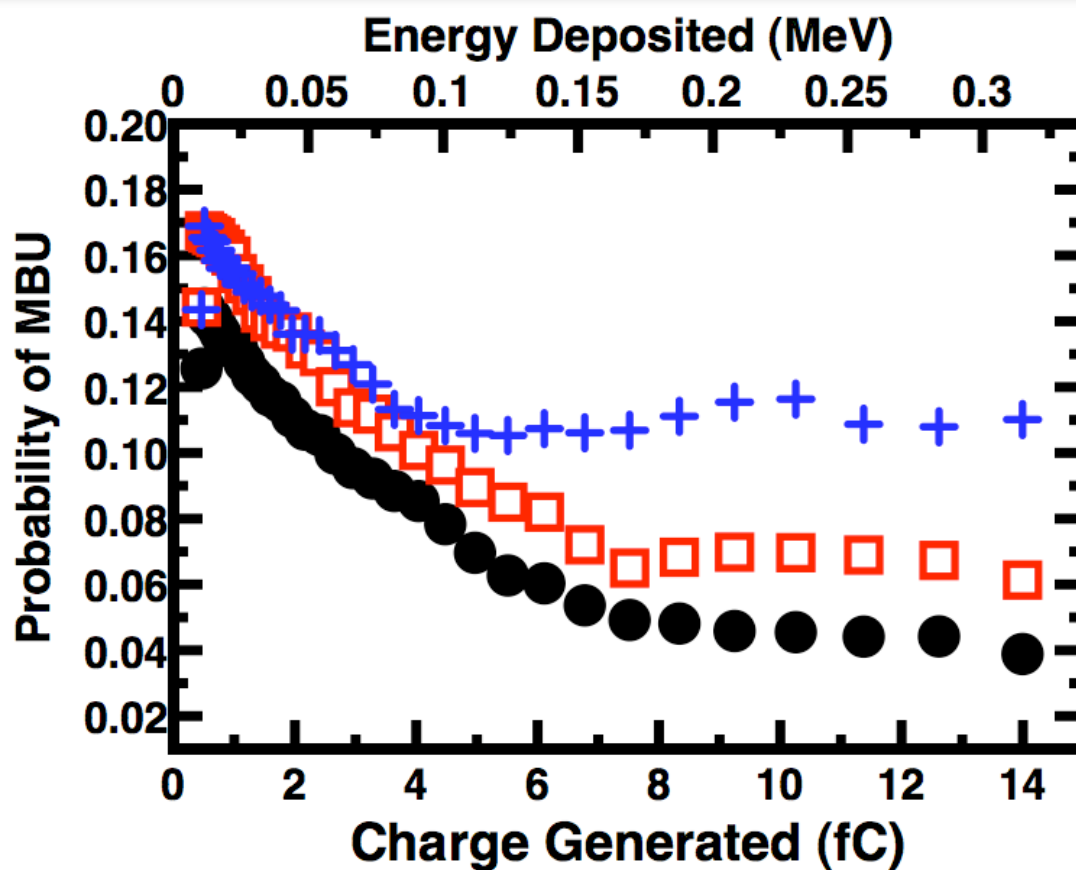
# Single-bit simulation in good agreement



- Circuit simulation suggest  $Q_{\text{crit}} = 4 \text{ fC}$
- Simulation in agreement with experimental data at  $Q_{\text{crit}}$



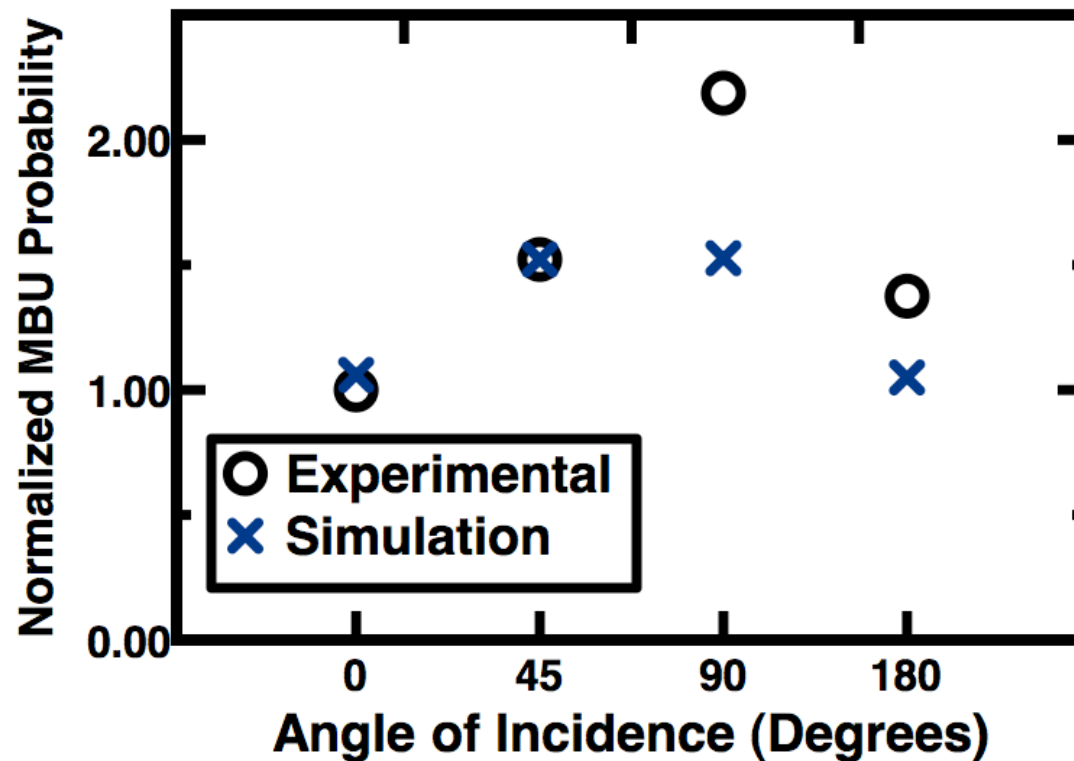
# Multiple-bit probability depends on orientation



- Preferential direction from spacing and nuclear products



## Multiple-bit upset probability



- Simulation shows increased probability at grazing angles
- More calibration needed at 90°





## Conclusions

- Multiple-bit upset is increasing for highly-scaled devices
- Neutron irradiation has been modeled using MRED for a TI 90 nm CMOS technology
- SBU independent of device orientation
- Probability of MBU exhibits an angle dependence for neutron irradiation
  - Probability increases at grazing angles
  - Neutron testing must account for these dependencies



## Publications and talks

- A. D. Tipton, J. A. Pellish, P. R. Fleming, R. D. Schrimpf, R. A. Reed, R. A. Weller, M. H. Mendenhall, and L. W. Massengill, "High-energy neutron multiple-bit upset," presented at International Conference on IC Design and Technology, Austin, TX, 2007.
- A. D. Tipton, X. Zhu, H. Weng, J. A. Pellish, P. R. Fleming, R. D. Schrimpf, R. A. Reed, R. A. Weller, and M. Mendenhall, "Increased rate of multiple-bit upset at large angles of incidence," *IEEE Trans. Dev. Mat. and Rel.*, submitted for review.



## Future work

- TI 65 nm process
  - Device simulation of SRAM cell
  - NASA-GSFC/Vanderbilt proton and heavy-ion testing
  - Examine impact of angular dependence on error rate
- Proton effects
  - Proton-Induce SEE
  - Proton-induced MBU
  - Possible IBM collaboration
  - Proton ionization
- Dissertation Fall '08

